

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 10/553,573
Applicants: Christian DUSSARRAT, et al.
Filed Internationally: April 8, 2004
US National: October 17, 2005
Title: METHODS FOR PRODUCING SILICON NITRIDE FILMS
BY VAPOR-PHASE GROWTH
TC/A.U.: 1762
Examiner: Elizabeth A. Burkhart
Docket No.: Serie 6070
Customer No.: 40582

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action of January 5, 2009, please amend the application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims begin on page 3 of this paper.

Remarks begin on page 8 of this paper.